



Web Images Groups News Froogle Local **more »**

zernike used in semiconductor wafer aberratio Search [Advanced Search](#)
[Preferences](#)

Web

Results **21** - **30** of about **114** for **zernike used in semiconductor wafer aberration measurement**. (0.15 seconds)

SPIE Proceedings Vol. 2778

... Method of the System Error **Used** for CCD MTF ... of a Ray-Detector for Examination of

Semiconductor Devices in ... Generalization of the Van Cittert-**Zernike** Theorem to ...

www.spie.org/web/abstracts/2700/2778.html - 43k - Supplemental Result - [Cached](#) - [Similar pages](#)

[[More results from www.spie.org](#)]

[PDF] Wet-Etch Figuring: Optical Surfacing by Controlled Application of ...

File Format: PDF/Adobe Acrobat - View as HTML

... the **semiconductor** processing industry for critical **wafer** drying applications.

... Interferometric **measurements**. were taken along one line, and **used** to ...

www.llnl.gov/nif/ist/diffractive-optics/UCRL-JC-143914-spie_V4451.pdf - [Similar pages](#)

[PDF] Tanya E

File Format: PDF/Adobe Acrobat - View as HTML

Measurement of solar constant in near UV and visible wavelengths. Developed a new.

approach describing third order **aberration** fields of simple tilted and ...

www.coloradophotonics.org/PDF/Resumes/TonyaJewell.pdf - [Similar pages](#)

Department of Electrical Engineering

Topics include circuit analysis and simulation, **semiconductor** device fundamentals

and ... Optical materials and properties; third order **aberration** theory. ...

www.ee.utdallas.edu/gradcourse.html - 63k - [Cached](#) - [Similar pages](#)

oe magazine - progress report: 157-nm lithography prepares to graduate

Based on the **measurement** data obtained from large batches of finished ...

An overlay of 23 nm (mean +3 σ) on product **wafers** must be achieved and bettered. ...

oemagazine.com/fromTheMagazine/feb03/157.html - 41k - [Cached](#) - [Similar pages](#)

Integrated Circuits for 2003

... based **aberration** targets to measure individual **Zernike aberration** terms.

The optimum targets are inverse Fourier transforms of the **Zernike** polynomials ...

www.eecs.berkeley.edu/IPRO/Summary/03abstracts/chapter4.html - 107k - [Cached](#) - [Similar pages](#)

[PDF] Initial Results from the EUV Engineering Test Stand

File Format: [PDF/Adobe Acrobat - View as HTML](#)
used as a control to reproduce across-plane focus on subsequent **wafers** as ...
was **used** to measure the separation between the marks. These **measurements** were ...
[www.eecs.berkeley.edu/~jbokor/Full_text_pubs/2-177.pdf](#) - [Similar pages](#)
[[More results from www.eecs.berkeley.edu](#)]

[PDF] [Preparations for EUV interferometry of the 0.3 NA MET optic](#)

File Format: [PDF/Adobe Acrobat - View as HTML](#)
annular **Zernike** polynomials yields an RMS wavefront **aberration** magnitude of 0.56
nm (λ ... **used** in the **measurement** of 0.1 NA optics in the past. ...
[repositories.cdlib.org/cgi/viewcontent.cgi?article=1452&context=lbln1](#) - [Similar pages](#)

[PDF] [Engineering and Laboratory Notes](#)

File Format: [PDF/Adobe Acrobat](#)
semiconductor wafers or chips, by optical polishing their ... other hand the
Zernike coefficients obtained by interfero-. metric **measurements** often cover ...
[ao.osa.org/ViewMedia.cfm?id=65278&seq=0](#) - [Similar pages](#)
[[More results from ao.osa.org](#)]

Semiconductor International - [Improved Imaging Metrology Needed ...](#)

... The International Technology Roadmap for **Semiconductors** (ITRS) 1 ... linear sensitivity
model can be **used** has been ... FAMIS measures the **Zernike** coefficients Z 9 , Z ...
[www.reedelectronicsgroup.com/semiconductor/article/CA82791?pubdate=4%2F2001](#) - [Supplemental Result - Similar pages](#)



Result Page: [Previous](#) 1 2 3 4 5 6 7 8 9 [Next](#)

[zernike used in semiconductor wafer](#) [Search](#)

[Search within results](#) | [Language Tools](#) | [Search Tips](#)

[Google Home](#) - [Advertising Programs](#) - [Business Solutions](#) - [About Google](#)

©2005 Google